IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLN. OF:

TANABE et al

SERIAL NO.:

09/612,551

FILED:

July 7, 2000

FOR:

SEMICONDUCTOR THIN FILM FORMING SYSTEM

DOCKET:

NEC WNZ-2212

The Commissioner of Patents & Trademarks Washington, D.C. 20231

PRIOR ART DISCLOSURE STATEMENT

Dear Sir:

In connection with the above-entitled matter, Applicants hereby attach U.S. Patent Office Form PTOL-1449, including copies of the prior art references listed therein. These references (other than the Reid et al and the Bird et al references) are discussed in the specification. The claims in the present application are believed to be patentably distinguished over these references.

This prior art disclosure statement is being made pursuant to the duty of disclosure imposed by law and formulated in 37 CFR 1.56(A). No representation is made that the information thus disclosed in fact constitute prior art or that it is the closest prior art, inasmuch as 37 CFR 1.56(A) relies on a materiality concept which depends on subjectivity.

In the event there are any fee deficiencies or additional fees are payable please charge them (or credit any overpayment) to our Deposit Account No. 08-1391.

Respectfully submitted

Norman P. Soloway

Attorney for Applicants

Reg. No. 24,315

HAYES, SOLOWAY,
HENNESSEY, GROSSMAN
& HAGE, P.C.
175 CANAL STREET
MANCHESTER, NH
03101-2335 U.S.A.

603-668-1400



CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner of Patents, Washington, D.C. 20231 on ______ at Manchester, New Hampshire.

TECHN

HAYES, SOLOWAY,
HENNESSEY, GROSSMAN
& HAGE, P.C.
175 CANAL STREET
MANCHESTER, NH
03101-2335 U.S.A.

603-668-1400